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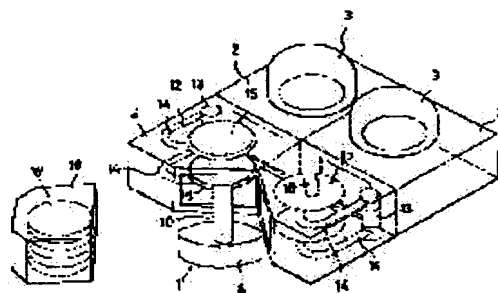
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(54) TREATING DEVICE FOR SUBSTRATE HAVING LOAD LOCKING CHAMBER

(57)Abstract:

PROBLEM TO BE SOLVED: To efficiently execute a treatment by diminishing the volume of the load locking chamber of a treating device having the load locking chamber.

SOLUTION: A handler unit 12 which carries substrates W into a treating chamber 2 and ejects the substrates W out of the inside of the treating chamber 2 is arranged in the load locking chamber 4. This handler unit 12 is constituted by freely turnably supporting the base ends of two pieces of upper and lower curved arms 14 at a shaft 13 within a horizontal plane and providing the front ends of the respective arms 14 with hand parts 15. These hand parts 15 are formed to an approximate circular shape and projecting lines holding the substrates W are formed at their peripheral edges.



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